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INFORMATION DISCLOSURE STATEMENT BY APPLICANT		Application Number	10/826,007
		Filing Date	04/16/2004
(use as many sheets as necessary)		First Named Inventor	Hongxing TANG et al.
		Group Art Unit	2855
Sheet 1 of 1		Examiner Name	Unassigned
		Attorney Docket Number	049411-0268

U.S. PATENT DOCUMENTS						
Examiner Initials*	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			
JLB	A1	2003/0062193	A1	THAYSEN et al.	04/03/2003	
	A2	2003/0089182	A1	THAYSEN et al.	05/15/2003	

FOREIGN PATENT DOCUMENTS							
Examiner Initials*	Cite No. ¹	Foreign Patent Document			Name of Patentee or Applicant of Cited Documents	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
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NON PATENT LITERATURE DOCUMENTS				
Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.) date, page(s), volume-issue number(s), publisher, city and/or country where published.		
JLB	A3	HARLEY et al., "High-Sensitivity Piezoresistive Cantilevers Under 1000 A Thick," Physics Letters, Vol. 75, No. 2, American Institute of Physics, July 12, 1999, pp. 289-291.		
	A4	HARLEY et al., "1/f Noise Consideration for The Design and Process Optimization of Piezoresistive Cantilevers," Journal of Microelectromechanical Systems, Vol. 9, No. 2, IEEE, June 2, 2000, pp. 226-235.		
	A5	HUTTER et al., "Calibration of Atomic-Force Microscope Tips," Rev. Sci. Instrum., Vol. 64, No. 7, American Institute of Physics, July 1993, pp. 1868-1873.		
	A6	KUCZYNSKI, "Effect of Elastic Strain on The Electrical Resistance of Metals," Physical Review, Vol. 94, No. 1, April 1, 1954, pp. 61-64.		
	A7	LI et al., "Thin Gold Film Strain Gauges," J. Vac. Sci. Technol., Vol. 12, No. 3, American Vacuum Society, May 1994, pp. 813-819.		
	A8	PARKER et al., "Electrical Resistance-Strain Characteristics of Thin Evaporated Metal Films," Journal of Applied Physics, Vol. 34, No. 9, September 1963, pp. 2700-2708.		
	A9	Physics Web, "Nanoelectromechanical Systems Face The Future," Physics World Magazine, Vol. 14, Issue 2, February 2001, http://physicsweb.org/article/world/14/2/8 .		
	A10	REID et al., "6-MHz 2-N/m Piezoresistive Atomic-Force-Microscope Cantilevers With INCISIVE Tips," Journal of Microelectromechanical Systems, Vol. 6, No. 4, IEEE, December 4, 1997, pp. 294-302.		
	A11	THAYSEN et al., "Polymer-Based Stress Sensor With Integrated Readout," Journal of Physics D: Applied Physics, Vol. 35, Institute of Physics Publishing Ltd., 2002, pp. 2698-2703.		
	A12	TORTONESE et al., "Atomic Resolution With An Atomic Force Microscope Using Piezoresistive Detection," Applied Physics Letters, Vol. 62, No. 8, American Institute of Physics, February 22, 1993, pp. 834-836.		
	A13	YANG et al., "Monocrystalline Silicon Carbide Nanoelectromechanical Systems," Applied Physics Letters, Vol. 78, No. 2, American Institute of Physics, January 8, 2001, pp. 162-164.		

Examiner Signature	<i>James P. Bente</i>	Date Considered	19 December 2005
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